

# MACHINE PROTECTION SYSTEM RESEARCH AND DEVELOPMENT FOR THE FERMILAB PIP-II PROTON LINAC\*

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## Abstract

The Fermilab Proton Improvement Plan (PIP-II) includes a high intensity proton linac being designed to support a world-leading physics program at Fermilab. Initially it will provide high intensity beams for Fermilab's neutrino program with a future extension to other applications requiring an upgrade to CW linac operation (e.g. muon experiments). The machine is conceived to be 2 mA CW, 800 MeV H- linac capable of working initially in a pulse (0.54 ms, 20 Hz) mode for injection into the existing Booster. The planned upgrade to CW operation implies that the total beam current and damage potential will be greater than in any present HEP hadron linac. To mitigate the primary technical risk and challenges associated with PIP-II, an integrated system test for the PIP-II front-end technology is being developed. As part of the R&D a robust Machine Protection System (MPS) is being designed and tested. This paper describes the progress and challenges associated with the MPS.

## Introduction

PIP-II is being designed and constructed to be a CW-compatible, pulsed H- SRF linac. It is an essential part of the planned program of upgrades to the existing Fermilab accelerator injection complex. To mitigate some risk and to validate the concept of the front-end associated with the PIP-II machine, a test accelerator is under construction. The test machine is known as the PIP-II Injector Test (PIP2IT) [2]. It includes a 10 mA DC, 30 keV H- ion source, a 2 m-long Low Energy Beam Transport (LEBT), a 2.1 MeV CW RFQ, along with a Medium Energy Beam Transport (MEBT) that feeds the first of 2 cryomodules. This increases the beam energy to about 25 MeV. A high Energy Beam Transport section (HEBT) takes the beam to a dump. The length of beam pulses in the machine is dictated by a chopper located between the last two solenoids in the LEBT. The chopper can provide 1  $\mu$ sec - 16 msec pulses with a frequency that ranges from single shots to 60 Hz. The ion source, LEBT, RFQ, and initial version of the MEBT have been built, installed, and commissioned. Part of the ongoing R&D program associated with this setup includes the development and integration of a Machine Protection System into the complex capable of protecting the machine from beam induced damage while monitoring the chopper operation. An upgrade to quasi-CW operation is planned as a future mode of operation for the machine to deliver beam simultaneously to multiple users. This planned upgrade to CW operation implies that the total beam current and damage potential will be greater than in any present HEP hadron linac

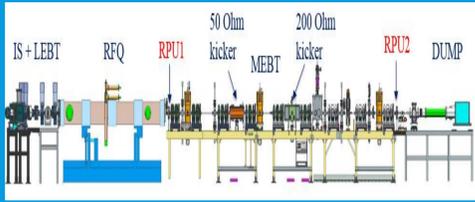


Figure 1: Machine Layout of PIP II Facility



Figure 2: PXIE Facility

## Protection System Overview

The PIP-II MPS will comprise of a logic system that takes in signals from various sub-systems and drives permits to beam enabling devices. These devices interacting with the MPS will be divided into primary and secondary categories based on how critical they are to mitigating beam damage as illustrated in Figure 3. Primary devices are main actuators for beam and should guarantee that, when they function properly, no dramatic damage can be caused by the beam even if protection through secondary devices fail. Both categories include sensing and beam-inhibiting devices. The primary beam-inhibiting devices are located at the Ion Source and in the LEBT section. They will include the LEBT chopper, the LEBT dipole, the Ion Source modulator and the Ion Source bias power supply. The secondary beam inhibiting devices are those devices whose malfunctioning will not create dramatic damage; either because the effects can be detected and mitigated by the primary devices, or because the inclusion of the devices into the MPS is for the protection of the device itself (e.g. insertion devices). The secondary devices further decrease the probability of damage and possible irradiation of components. The list of secondary sensing devices includes: the system providing the beam request sequence from the accelerator complex, status signals from the Linac subsystems, e.g. RF amplifiers, magnet power supplies, quench detection system, cryogenic system, LCW, the control system etc. In addition, these also include malfunctioning subsystems which can affect the beam delivery (e.g. RF amplifier) thereby dropping the Linac beam permit

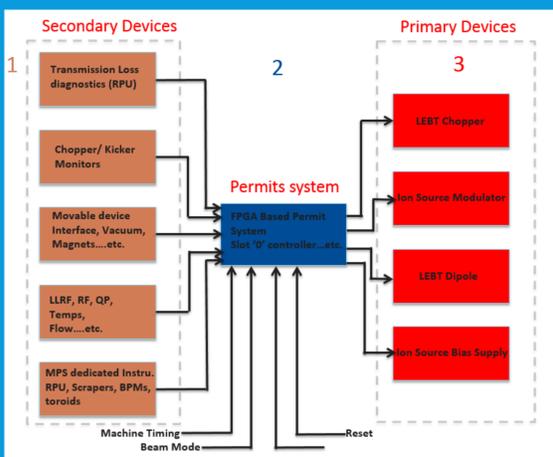


Figure 3: MPS Overview



TTL to LVDS converter cards  
5V or 3.3V TTL/CMOS logic  
level is OK

